Table VI. Torsional Angles within the Phosphazene Ring

Bonds	Angle, deg	Bonds	Angle, deg
P(1)-N(1)-P(3)-N(3)	-13.9	N(3)-P(2)-N(2)-P(1)	15.1
N(1)-P(3)-N(3)-P(2)	6.6	P(2)-N(2)-P(1)-N(1)	-20.5
P(3)-N(3)-P(2)-N(2)	-7.0	N(2)-P(1)-N(1)-P(3)	20.4

protonated segment. This could suggest some d_{π} - p_{π} bonding involvement in the exocyclic P-N bonds. Of special interest is the angle P(3)-N(1)H-P(1), which is 126.9°. This can be compared to the 123° angle reported for a cyclotriphosphazene^{3,5} and the 132° angle reported for the P-NH-P unit in II.⁵ Apparently the bond angle at nitrogen is especially flexible and it responds more to the demands of the ring geometry as a whole than to the hybridization requirements at a particular site. The endocyclic ring angles at phosphorus are in the range of 109.6-114.5°, values that are unusally narrow compared with many other cyclotriphosphazenes. Similar effects were reported for II.⁵ This could be a consequence of reduced ring π bonding. The exocyclic N-P-N bond angles, which fall within the range 103.0-108.0°, Ring, et al.

are normal for cyclotriphosphazenes,²⁷ and, as expected, the N(exo)-P-N(exo) planes are oriented approximately at right angles to the adjacent N(ring)-P-N(ring) plane.

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Registry No. $[HN_{3}P_{3}(NMe_{2})_{6}]_{2}[Mo_{6}O_{19}], 37369-90-7; MoO_{3}, 1313-27-5.$

Supplementary Material Available. A listing of observed and calculated structure factor amplitudes will appear following these pages in the microfilm edition of this volume of the journal. Photocopies of the supplementary material from this paper only or microfiche ($105 \times 148 \text{ mm}, 20 \times \text{reduction}, \text{negatives}$) containing all of the supplementary material for the papers in this issue may be obtained from the Journals Department, American Chemical Society, 1155 16th St., N.W., Washington, D. C. 20036. Remit check or money order for \$4.00 for photocopy or \$2.00 for microfiche, referring to code number INORG-73-2963.

(27) Reference 3a, Appendix I.

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Pyrolysis of Halodisilanes and the Formation and Insertion Reactions of Chlorosilylene and Fluorosilylene

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The pyrolysis of Si_2F_6 , FSi_2H_5 , $ClSi_2H_5$, 1,1- $F_2Si_2H_4$, 1,1- $Cl_2Si_2H_4$, and $((CH_3)SiHCl)_2$ was examined as neat and in the presence of other silanes. The results from these pyrolyses demonstrated that all six disilanes decomposed into a silylene and a silane. In $((CH_3)SiHCl)_2$ the relative rate of the 1,2 hydrogen shift compared to the 1,2 chlorine shift was 4.4 ± 0.4 . 1,2 halogen shifts were not observed in 1,1- $F_2Si_2H_4$ or 1,1- $Cl_2Si_2H_4$. The insertions of silylenes into the silicon-hydrogen bonds in ethylsilane were examined. The product ratios coupled with assumptions of the half-lives of the silylenes led to the following order for silylene insertion rates: $SiH_2 > ClSiH > FSiH >> Cl_2Si$, F_2Si .

Introduction

It was suggested that $Si_2(CH_3)_5H$ thermally decomposed by a 1,2 hydrogen shift to form $HSi(CH_3)_3$ and $Si(CH_3)_2$.¹ It has now been demonstrated that Si_2H_6 ,^{2,3} $CH_3Si_2H_5$,⁴ and 1,2- $(CH_3)_2Si_2H_4$ ⁴ decompose *via* 1,2 hydrogen shifts producing a silane and a silylene. Methoxydisilanes also decompose into a silylene and a silane *via* a 1,2 methoxy shift.^{5,6} In the above reactions, the silylenes have been chemically trapped.

It has also been suggested that Si_2F_6 decomposes similarly *via* a 1,2 fluorine shift.⁷ Dichlorosilylene has been generated and chemically trapped in the flow pyrolysis of Si_2Cl_6 and C_2H_2 .⁸

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We have examined the pyrolysis (under flow conditions with low-temperature removal of products) of a number of substituted disilanes in order to determine the following: (i) the relative rate of a 1,2 hydrogen shift vs. a 1,2 chlorine shift when both hydrogen and chlorine are in the same environment; (ii) the effects of environment on the rates of 1,2 hydrogen shifts; (iii) the relative rates of SiF₂, SiCl₂, HSiF, HSiCl, and SiH₂ insertion into silicon-hydrogen bonds.

Experimental Section

The silanes and alkylsilanes used were prepared by the reduction of the corresponding chloro compounds with LiAlH₄ or LiAlD₄. Hexafluorodisilane was prepared by reaction of Si₂Cl₆ with SbF₃.⁹ 1,1-Dichlorodisilane was obtained from the reaction of Si₂H₆ with HCl over Al₂Cl₆.¹⁰ while 1,1-F₂Si₂H₄ was obtained from the reaction of 1,1-Cl₂Si₂H₄ with SbF₃.¹¹ Chlorodisilane and FSi₂H₅ were prepared by chlorination of Si₂H₆¹⁰ followed by fluorination of ClSi₂H₅ with SbF₃ in a flow reactor. The new compound 1,2-dichloro-1,2-dimethyldisilane, sym-Cl₂Si₂H₄ (CH₃)₂, was prepared by the reaction of 1,2-(CH₃)₂Si₂H₄ with AgCl in a flow reactor as previously described¹² with the cold trap at -45° and the reactor at 25°.

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Table I. Neat Pyrolyses of Halodisilanes

Expt	Reagent consumed (mmol)	Temp, °C	Cold trap, °C	Volatile products (mmol)
1	$Si_{2}F_{6}$ (0.8)	405	-55	$\operatorname{SiF}_{4}(0.8)$
2	$1, 1-F_{2}Si_{4}H_{4}$ (0.3)	400	-78	F_2SiH_2 (0.25), $F_2Si_3H_6$ (0.08)
3	$FSi_2H_5(0.5)$	390	-78	H_2 (0.01), SiH ₄ (0.06), FSiH ₃ (0.28),
				$Si_{2}H_{6}$ (0.01), 1-FSi ₃ H ₇ (0.08)
4	$1,1-Cl_2Si_2H_4$ (0.2)	370	-23	H_2 (0.03), SiH ₄ (0.04), HCl (0.02),
				Cl_2SiH_2 (0.08)
5	$ClSi_2H_s$ (0.7)	390	-63	H_2 (0.02), SiH ₄ (0.22), HCl (0.01),
				$ClSiH_3$ (0.18), 1- $ClSi_3H_7$ (0.16)
6	$sym-Cl_2Si_2H_2(CH_3)_2$ (0.5)	395	0	H_2 (0.02), HCl (0.04), ClSi H_2 CH ₃ (0.35),
				Cl_2SiHCH_3 (0.08), $Cl_2Si_3H_3(CH_3)_3$ (0.04)

The compound sym-Cl₂Si₂H₂(CH₃)₂ was purified by trap to trap distillations. The product was found in a trap cooled to -45° having passed a trap cooled to -36° . The infrared spectrum of this compound consisted of the following absorptions (cm⁻¹): 2990 (w), 2160 (s), 1410 (w), 1265 (m), 872 (s), 788 (s), 735 (s), 705 (w), 625 (w), 542 (w), 509 (s). The mass spectrum at 10 V was due to the following heavy-atom ions (m/e in parentheses): Si₂C₂Cl₂⁺ (44.6), Si₂CCl₂⁺ (5.3), Si₂C₂Cl⁺ (2.4), CSiCl₂⁺ (5.3), CSiCl⁺ (100), plus ions of lower mass. The relative intensities at m/e 158, 160, and 162 should be 100:72:15 based on isotope ratios of ³⁵Cl, ³⁷Cl, ²⁸Si, ²⁹Si, and ³⁰Si and were 100:70:17. The neat proton nmr spectrum with TMS as an internal standard consisted of a CH_3 doublet at δ 0.70 and a poorly resolved Si-H quartet at δ 4.93 with relative intensities of 3.1:1. The absence of resonances between δ 3 and 4 clearly demonstrates the absence of $CH_3SiCl_2SiH_2CH_3$ and $(CH_3)_2Si_2H_3Cl^{12}$ The appearance of the CH₃SiCl₂⁺ in the mass spectrum is due to migrations in the mass spectrum.

1. Neat Pyrolyses. Neat pyrolyses were carried out in Pyrex or Vycor tubes 9 mm in diameter and 15-20 cm long, which were wrapped with a heating tape and insulated with several layers of asbestos tape. A well was provided for a thermometer in order to monitor the temperature. Temperature control was effected by means of a Variac transformer. The thermal zone was connected to a "U" cold trap and an automatic Toepler pump for cycling the reactants. The cold trap removed any products less volatile than the reagent undergoing thermal decomposition. The inner wall of the pyrolyses tubes were coated with a silicon mirror to prevent Pyrex catalysis. No decomposition of the disilanes occurred when the disilanes were cycled at 25°. The results from typical neat decompositions are listed in Table I.

The reagents used in these and other thermal decompositions and the known products of these reactions were identified and checked for purity both by infrared spectra, which were identical with those reported, and by mass spectra consistent with the formula. In addition, logical impurities (Cl₂SiH₂ and SiH₄ for ClSiH₃) were demonstrated absent by the absence of either strong infrared bands from the infrared spectra or parent ions from the mass spectra under conditions where the parent ions were easily detected. The purity of the compounds 1,1-F₂Si₂H₄, FSi₂H₅, 1,1-Cl₂Si₂H₄, and ClSi₂H₅ were also confirmed by proton nmr spectra which were identical with those reported in the literature.13

The fractionation temperatures used to separate the products in Tables I and II are listed in Table III while the new compounds generated were identified as described in section 3.

2. Pyrolyses of Halodisilanes in the Presence of Other Silanes. The compounds thermalized neat in section 1 were also decomposed in the presence of thermally stable silanes. The results of these experiments are listed in Table II. These decompositions were carried out in the same manner as described in section 1. The gas-phase ratios were calculated from the relative vapor pressures measured at the cold-trap temperatures and the mole fractions of the compounds present. The products of the decompositions in the presence of deuteriosilanes were demonstrated free of silicon-deuterium bonds by the absence of silicon-deuterium stretching frequencies (1600 cm⁻¹). The new compounds obtained were identified as described in section 3.

3. Identification of New Products. The following four compounds produced as described in Table I (experiments 2, 3, 5, and 6) were identified as follows.

Experiment 2. $F_2Si_3H_6$. This compound was contained in a trap cooled to -63° . The mass spectrum at 18 V consisted of the following heavy-atom fragments: $F_2Si_3H_x^+$ (16), $FSi_3H_x^+$ (2),

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 $F_2Si_2H_x^+$ (9), $Si_3H_x^+$ (33), $FSi_2H_x^+$ (20), $F_2SiH_x^+$ (8), $Si_2H_x^+$ (100), $FSiH_x^+$ (23). The infrared spectrum consisted of the following absorptions (cm⁻¹): 2150 (s), 935 (s), 870 (s), 700 (s), 665 (m), 555-505 (w). The band at 700 cm⁻¹ is a doublet very much like the doublet in Si₃H₈ at 711 cm⁻¹.¹⁴

Experiment 3. 1-FSi₃H₇. 1-Fluorotrisilane was purified by distillation through a trap cooled to -63° and contained in a trap cooled to -95° . It was identified by a mass spectrum at 15 V of the following heavy-atom ions: $FSi_3H_x^+$ (14), $Si_3H_x^+$ (22), $FSi_2^ H_{x}^{+}$ (53), $Si_{2}H_{x}^{+}$ (100). The proton nmr spectrum consisted of a complex multiplet (-Si₂H₅) at δ 3.35 and a doublet (H₂SiF-) at δ 5.35 with J_{H-F} = 43 Hz of relative integrated intensity of about 3 (calculated 2.5). The infrared spectrum consisted of the following absorptions (cm⁻¹): 2170 (s), 1270 (w), 940 (s), 900-860 (vs), 795 (m), 730 (s), 700 (s), 522 (m).

Experiment 5. 1-ClSi₃H₇. This compound was obtained by fractionation through $a - 63^{\circ}$ trap and contained in a trap cooled to -95° . The compound was identified by the following spectra. The mass spectrum at 70 V consisted of the following heavy-atom fragments: $\text{CISi}_3 \text{H}_x^+$ (18), $\text{CISi}_2 \text{H}_x^+$ (43), $\text{Si}_3 \text{H}_x^+$ (21), $\text{CISi} \text{H}_x^+$ (47), $\text{Si}_2 \text{H}_x^+$ (60), CI^+ (100). The proton nmr spectrum consisted of a triplet (ClSiH₂-) at & 4.92, a triplet (-SiH₃) at & 3.42, and a complex multiplet (-SiH, -) at δ 3.55. The integrated intensity of the resonance at δ 4.92 divided by the intensities at δ 3.55 and 3.42 was 0.55 (calculated 0.4). The infrared spectra consisted of the following absorptions (cm⁻¹): 2170 (s), 1267 (w), 933 (s), 880-870 (s), 815 (m), 795 (m), 766 (m), 718 (m), 690 (m), 540 (s).

Experiment 6. $Cl_2Si_3H_3(CH_3)_3$. This compound was contained in a trap cooled to -23° . The identification was based solely on a mass spectrum which contained peaks due to the parent ions Cl₂Si₂- $(CH_3)_3H_{3-x}^+$. No heavier peaks were observed.

The following compounds and or mixtures produced as described in Table II (experiments 9-11, 15, and 16) were identified as described below.

Experiment 9. $C_2H_5Si_2H_2D_3$. This compound was identified by a proton nmr spectrum which consisted of two resonances at δ 0.87 (C_2H_5 -) and at δ 3.13 (-SiH₂D) of relative intensities of 2.7:1. The mass spectrum had a strong parent ion at m/e 93 and other peaks consistent for $C_2H_sSi_2H_2D_3$. A very weak envelope was observed with a highest mass at m/e 123 which was probably due to C2H5Si3H4D3.

Experiment 10. $C_2H_5Si_2H_4F$. Ethylfluorodisilane was obtained along with a large excess of $C_2H_5Si_2H_5$. The mass spectrum (15 V) of this mixture had weak peaks ending in the mass region m/e 110-104. The molecular weight of FSi₃H₇ is 110 while that of $C_2H_5Si_2H_4F$ is 108. When the mass spectrum of 1-FSi₃H₇ was removed from that of the mixture, considerable intensity remained at m/e 108. These results suggest that FSi₃H₂ and C₂H₅Si₂H₄F were both present. When FSi_2H_5 was decomposed in the presence of $C_2H_5SiD_3$ (experiment 11), the mass spectrum of the least volatile fraction now ended at m/e 111. The m/e 111 peak can be assigned to $C_2H_5SiD_2(D)HSiF$. This latter result further suggests that $C_2H_5Si_2H_4F$ was obtained from the pyrolysis of Si_2H_5F in the presence of C, H, SiH,.

The nmr spectrum of the least volatile fraction from the FSi₂H₅- $C_2H_5SiH_3$ pyrolysis was primarily that of $C_2H_5Si_2H_5$.¹⁵ In addition there were two resonances at δ 4.8 and 5.5. These two are probably from the fluorosilyl group in FSi_3H_7 and $C_2H_5Si_2H_4F$. If one assumes that the parent ions for FSi_3H_7 and $C_2H_5Si_2H_4F$ have the same intensity at the same pressure, then the mixture contained nearly

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Table II.	Pyrolyses	of Halodisilanes	in the Presenc	e of Other Silanes
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			Cold trap.	
Expt	Gas-phase ratio	Temp, °C	°C	Volatile products (mmol)
7	(CH ₃) ₂ SiH ₂ 80	415	-63	SiF ₄
	$\frac{1}{\operatorname{Si}_2 \mathrm{F}_6} = \frac{1}{1}$			
8	ClSiH ₃ 200	415	-63	SiF ₄
	$\frac{1}{\operatorname{Si}_2 \mathrm{F}_6} = \frac{1}{1}$			
9	$\frac{C_2 H_5 SiD_3}{2} = \frac{30}{2}$	400	-78	F_2SiH_2 (0.29), $C_2H_5Si_2H_2D_3$ (0.22)
	$1,1-F_2Si_2H_4$ 1			
10	$\frac{C_2H_5SiH_3}{M_2} = \frac{30}{M_2}$	390	-78	SiH_4 (0.06), $FSiH_3$ (0.28), $C_2H_5Si_2H_5$
	FSi_2H_5 1			$(0.28),^{\alpha}C_{2}H_{5}SI_{2}H_{4}F(\sim 0.015),^{\alpha}$ FSi ₂ H ₂ (~0.015) ^a
11	$C_2H_5SiD_3$ 8	390	-78	H_2 (0.02), SiH ₄ (0.04), FSiH ₃ (0.24),
	$-\frac{1}{\mathrm{FSi}_{2}\mathrm{H}_{s}}$			$C_2H_5Si_2H_2D_3$ and $C_2H_5Si_2HD_3F$ (0.24)
12	$(C_{2}H_{5})_{2}SiD_{2}$ 40	370	-23	SiH_4 (0.02), HCl (0.01), Cl ₂ SiH ₂ with
	$\frac{1.1-Cl_{1}Si_{1}H_{2}}{1} = \frac{1}{1}$			$(C_2H_5)_2SiD_2$
13	$C_{2}H_{2}SiH_{2}$ 13	370	-23	H ₂ (0.04), SiH ₄ (0.07), Cl ₂ SiH ₂ (0.07),
	$\frac{1}{1} \frac{1}{1} \frac{1}$			(no $C_2H_5Si_2H_3Cl_2$)
14	$N_2 = 10$	370	-23	HCl (0.02) , SiH ₄ (0.03) , Cl ₂ SiH ₆ (0.03)
	$\frac{1}{1.1-Cl_{1}} = \frac{1}{1}$			
15	$C_2H_2SiD_3$ 60	390	63	H ₂ (0.01), SiH ₄ (0.10), ClSiH ₂ (0.08), b
	$\frac{1}{ClSi_{\rm H}} = -\frac{1}{1}$			$C_2H_5Si_2H_2D_3$ and $C_2H_5SiHD_3Cl$ (0.14)
16	$C_2H_5SiH_2$ 60	390	-63	H ₂ (0.02), SiH ₄ (0.26), HCl (0.01), ClSiH ₂
	$\frac{1}{ClSi_{1}H_{2}} = \frac{1}{1}$			$(0.20), b C_2 H_5 Si_2 H_5 (0.20), c C_2 H_5 Si_2 H_4$ -
17	(C H) SiD 100	305	0	Cl (0.13) H (0.02) CH SiH Cl (0.13) CH SiH Cl
± /	$\frac{(C_2 \Pi_5)_2 S \Pi_2}{2} = \frac{100}{1}$	535	0	with $(C_2H_5)_2SiD_2$
	sym- $Cl_2 Sl_2 \Pi_2 (CH_3)_2 = 1$			

^a This mixture was analyzed by a combination of nmr and mass spectrometry. See details in section 3. ^b The CISiH₃ was reduced to SiH₄ for separation from ethylsilane. ^c From nmr integration of a mixture of $C_2H_5Si_2H_5$ and $CISi_2H_5$.

Table III. Slush-Bath Temperatures for Separation

	Te	mp, °C		Temp, °C	
Compd	Pass	Stop	Compd	Pass	Stop
Н,	-196		CH SiH, Cl	-95	-130
SiH	-160	-196	CH, SiHCl,	-78	-95
HCl, FSiH,	-145	-160^{a}	(CH ₃),SiH,	-95	-130
F ₂ SiH,	-130	-160	C ₂ H ₂ SiH ₂	-112	-130c
CISiH,	-112	-145 b	$(\tilde{C}_2H_5)_2\tilde{SiD}_2$	-63	-95
Cl, SiH,	-95	$-112^{b,c}$			

^a Not complete retention; nearly quantitative for very short fractionations. ^b Separation of ClSiH₃ and Cl₂SiH₂ by fractional distillation is not quantitative but this separation was not required. ^c The separation of Cl₂SiH₂ and C₂H₅SiH₃ was not completely quantitative but reasonable estimates of product yields were made from relative intensities of infrared bands.

equal quantities of these two compounds. With this assumption and with integrated nmr intensities, quantities of $C_2H_5Si_2H_4F$ and FSi_3H_7 could be estimated. It is obvious that the error in these values could be large.

Experiment 11. $C_2H_5Si_2HD_3F$. This compound was identified by a mass spectrum which contained a peak from the parent ion. No heavier peaks were observed.

Experiment 15. $C_2H_5Si_2HD_3Cl$. This compound was identified solely by a mass spectrum which contained a peak from the parent ion. No heavier peaks were observed.

Experiment 16. $C_2H_sSi_2H_4Cl$. This compound was identified by a mass spectrum containing peaks due to the following ions: $C_2H_xSi_2H_yCl^+(51)$, $CH_xSi_2H_yCl(9)$, $Si_2H_yCl(100)$, $C_2H_xSi_2H_y$ (44), and smaller ions. The nmr spectrum consisted of four resonances at δ 0.2 (- CH_2 -), 1.1 (CH_3 -), 3.73 (- SiH_2 -), and 4.85 (- SiH_2 -Cl). The integrated intensities were respectively 0.6:1:0.6:0.6. A sample was available and the spectrum was of poor quality. The infrared spectrum consisted of the following absorptions (cm⁻¹): 2970 (s), 2930 (m), 2890 (m), 2170 (vs), 1268 (w), 1075 (m), 1020 (m), 935 (s), 878 (s), 821 (s), 790-770 (vs), 537 (s).

Results and Discussion

1. Initial Decomposition Mode of Disilanes. The first step in the thermal decomposition of the disilanes investi-

gated in this study consisted solely of 1,2 atom shifts forming a silane and a silylene as found for ${\rm Si_2H_6}^{2,3}$ Most of these silylenes then underwent insertion into silicon-hydrogen or silicon-deuterium bonds. This general mechanism is consistent with the following experimental results.

Initial decomposition via silicon-hydrogen and siliconhalogen bond rupture can be eliminated since H₂ and HCl were very minor products and HF was not produced (no SiF₄). Another possibility, homolytic silicon-silicon bond rupture as found in $Si_2(CH_3)_6$,¹⁶ can also be eliminated. The decompositions of the disilanes in this investigation took place under the same conditions as our earlier Si_2H_6 pyrolysis.² The quantities decomposed were very similar indicating that the decomposition rates were all within an order of magnitude of each other. The activation energy for the decomposition of Si₂H₆ is 49.5 kcal/mol.¹⁷ The value of $D(SiH_3-SiH_3)$ is 81 kcal/mol¹⁸ and halogen substitution should increase this value when one considers the effects of halogen substitution on the per cent s character of the silicon orbitals in the silicon-silicon bond.¹⁹ Thus, if the disilanes decomposed by silicon-silicon rupture, the activation energies would be 80 kcal/mol or greater and the decomposition rates would be orders of magnitude lower than observed.

The absence of homolytic silicon-silicon bond rupture to form silyl radicals can be confirmed by the results of the decompositions in the presence of deuterated silanes (Table II). As an example, the pyrolysis of ClSi_2H_5 in the presence of a gas-phase 60:1 excess of $\text{C}_2\text{H}_5\text{SiD}_3$ produced SiH_4 and

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ClSiH₃. If ClSi₂H₅ had decomposed into SiH₃ and SiH₂Cl radicals, these radicals would have reacted with the excess $C_2H_5SiD_3$ to produce SiH₃D and DSiH₂Cl. The complete absence of these compounds demonstrates that homolytic silicon-silicon rupture did not occur. Similar results were obtained for all of the systems investigated. For Si₂F₆ the case is similar. If SiF₃ radicals were produced, the pyrolysis of Si₂F₆ in the presence of excess (CH₃)₂SiH₂ (80:1) or ClSiH₃ (200:1) should have resulted in the formation of HSiF₃. The complete absence of this product eliminates this mode of decomposition.

We conclude that the disilanes investigated decomposed into a silane and a silylene. This conclusion is further supported by the observed insertion of most of the silylenes into silanes forming the appropriate polysilanes (experiments 2, 3, 5, 6, 9-11, 15, and 16 in Tables I and II).

The results listed in Tables I and II can be used to determine the major decomposition modes for the disilanes investigated. When more than one mode is operative, the relative rates can be determined by the ratio of the monosilanes produced. For a compound XSi_2H_5 , the decomposition modes are represented by the reactions

$$XSi_2H_5 \xrightarrow{R_1} XSiH_3 + SiH_2$$
(1)

$$XSi_2H_5 \xrightarrow{k_2} XSiH + SiH_4$$
 (2)

The ratio k_1/k_2 can be equated to (yield of XSiH₃)/(yield of SiH₄) when XSiH₃ is formed only by reaction 1 and SiH₄ is formed only by reaction 2 and when these compounds do not decompose or react once they are formed. We can demonstrate that these conditions were met in our system with estimated errors of less than 10%.

The silylene radicals (SiH₂ or XSiH) could insert into the trapping alkylsilane (reaction 3), into a product silane, or

$$SiH_2 + RSiH_3 \rightarrow RSi_2H_5$$
(3)

into the reactant disilane or could polymerize on the wall. In the reactions listed in Table II, the alkylsilanes were present in the gas phase in high concentrations compared to either the reactant disilane or the product silanes so that silylene insertions into the reactant disilane or the product silanes can be eliminated. It has been demonstrated that alkylsilanes trap silylenes as well as SiH₄ and much better than halosilanes.²⁰ The alkyldisilanes once formed were removed from the stream by the cold trap. To demonstrate that these alkyldisilanes did not decompose once formed, we can cite the following typical result. In the pyrolysis of $ClSi_2H_5$ in the presence of $C_2H_5SiD_3$ in a 60:1 excess, the products were C2H5SiD2SiDH2 and C2H5SiD2SiDHC1. If these compounds decomposed, SiH₂D₂ and SiD₂HCl would have been produced.⁴ The absence of SiH_2D_2 and SiD_2HCl demonstrates that the insertion products were completely removed by the cold trap.

Once formed, the compounds SiH_4 and $XSiH_3$ did not decompose to any great extent due to their greater thermal stability compared to the disilanes. This contention is verified by the low yield of H_2 . The last potential problem is that of polymer decomposition. In a kinetic investigation of the pyrolysis (static conditions) of Si_2H_6 a polymer was obtained. The decomposition of this polymer was slow compared to that of disilane and the main product was H_2 .²¹ In our flow system, most of the polymer would deposit outside of the thermal zone further decreasing its decomposition. The suggestion that polymer decomposition did not affect our $XSiH_3:SiH_4$ product ratios is consistent with the fact that these ratios are similar in Tables I and II where per cent polymer formation was significantly different.

We conclude that the data in Tables I and II (especially II) can be used to determine the relative ratio of k_1/k_2 . The results from Tables I and II lead to the following ratios for the decomposition of the disilanes investigated in this study

$$Si_2F_6 \longrightarrow SiF_2 + SiF_4$$
 (4)

$$1,1-F_2Si_2H_4 \longrightarrow SiH_2 + F_2SiH_2$$
(5)

$$FSi_{2}H_{5} \stackrel{k_{6}}{\underset{k=6}{\leftarrow}} SiH_{2} + FSiH_{3}$$
(6)

$$FSi_{2}H_{5} \stackrel{\underline{k_{7}}}{\underset{\underline{k_{7}}}{\longleftarrow}} FSiH + SiH_{4}$$
(7)

$$k_6/k_7 = 5 \pm 1$$

$$1,1-\operatorname{Cl}_{2}\operatorname{Si}_{2}\operatorname{H}_{4} \xrightarrow{\frac{R_{2}}{k}}_{h_{-8}} \operatorname{SiH}_{2} + \operatorname{Cl}_{2}\operatorname{SiH}_{2}$$
(8)

$$1,1-\operatorname{Cl}_{2}\operatorname{Si}_{2}\operatorname{H}_{4} \xrightarrow{k_{9}}{\underset{k_{-9}}{\overset{\operatorname{KS}}{\longleftarrow}} \operatorname{SiCl}_{2} + \operatorname{SiH}_{4}$$
(9)

$$k_{\rm s}/k_{\rm g}\simeq 1^{22}$$

$$\operatorname{ClSi}_{2}\operatorname{H}_{5} \xleftarrow{k_{10}}_{k_{-10}} \operatorname{SiH}_{2} + \operatorname{ClSiH}_{3}$$
(10)

$$\operatorname{CISi}_{2}\mathrm{H}_{5} \xrightarrow[k_{-11}]{k_{11}} \operatorname{CISiH} + \operatorname{SiH}_{4}$$
(11)

$$k_{10}/k_{11} = 0.80 \pm 0.1$$

$$sym-\operatorname{Cl}_{2}\operatorname{Si}_{2}\operatorname{H}_{2}(\operatorname{CH}_{3})_{2} \xrightarrow{k_{12}} \operatorname{ClSiCH}_{3} + \operatorname{ClSiH}_{2}\operatorname{CH}_{3}$$
(12)

$$sym-\text{Cl}_2\text{Si}_2\text{H}_2(\text{CH}_3)_2 \xrightarrow{\gamma_{13}} \text{HSiCH}_3 + \text{Cl}_2\text{SiHCH}_3$$
(13)

 $k_{12}/k_{13} = 4.4 \pm 0.4$

The results from the decomposition of sym-Cl₂Si₂H₂(CH₃)₂ (eq 12, 13) suggest that when a Cl atom and an H atom are in an identical ground state environment, the H atom shift is considerably more favored than the Cl shift. This result is in agreement with our data on 1,1-Cl₂Si₂H₄ where no Cl atom shift was observed while both types of H atoms apparently underwent 1,2 hydrogen shifts.

2. Relative Insertion Rates of SiH₂, HSiCl, HSiF, SiF₂, and SiCl₂ into Si-H Bonds. It has been established that SiH₂ insertions into silicon-hydrogen bonds are very facile reactions.^{2,3} It has been estimated that these insertion reactions have nearly zero activation energies.¹⁷ In contrast, it appears that SiF₂ is unreactive in the gas phase with a "half-life" of 150 sec.²³ Thus as expected, SiF₂, from the Si₂F₆ pyrolysis, did not insert into the silicon-hydrogen bonds in (CH₃)₂SiH₂ or ClSiH₃ in the gas phase. Similarly SiCl₂, generated from 1,1-Cl₂SiH₂, did not insert into the silicon-hydrogen bonds in C₂H₅SiH₃. Chlorosilylene and FSiH are intermediate between SiH₂ and SiCl₂ or SiF₂ and one might expect to observe their insertions into siliconhydrogen bonds.

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⁽²²⁾ The $Cl_2SiH_2:SiH_4$ product ratio varied considerably from Table I to Table II. We have listed the result from Table II where a silylene trapping agent was present.

⁽²³⁾ P. L. Timms, R. A. Kent, T. C. Ehlert, and J. L. Margrave, J. Amer. Chem. Soc., 87, 2824 (1965).

Chlorodisilane decomposes by eq 10 and 11. From the determination of the SiH₄:ClSiH₃ ratio we have a measure of the ClSiH:SiH₂ ratio produced from ClSi₂H₅. If the half-lives of ClSiH and SiH₂ are the same, this ratio (1.25) would approximate the ClSiH:SiH₂ gas-phase ratio in our system. Since ClSiH probably has a longer half-life than SiH₂, this ratio would be a lower limit. In the pyrolysis of ClSi₂H₅ in the presence of $C_2H_5SiH_3$, SiH₂ and ClSiH reacted with $C_2H_5SiH_3$ forming $C_2H_5Si_2H_5$ and $C_2H_5SiH_2$. SiH₂Cl in a ratio of 1.54, respectively. This result suggests that the lower limit of k_{14}/k_{15} is about 2.

$$\operatorname{SiH}_{2} + \operatorname{C}_{2}\operatorname{H}_{5}\operatorname{SiH}_{3} \xrightarrow{k_{14}} \operatorname{C}_{2}\operatorname{H}_{5}\operatorname{Si}_{2}\operatorname{H}_{5}$$
(14)

 $ClSiH + C_2H_5SiH_3 \xrightarrow{h_{15}} C_2H_5SiH_2SiH_2Cl$ (15)

If the half-life of ClSiH is much longer than that of SiH_2 , this ratio would be considerably greater than 2.

Fluorodisilane decomposed via eq 6 and 7 to form SiH₂ and FSiH in a ratio of 5 ± 1 . Since the half-life of FSiH is undoubtedly greater than that of SiH₂ the FSiH:SiH₂ ratio in our system was 0.2 or greater. Since the ratio of C₂H₅Si₂-H₅ to C₂H₅SiH₂Si(F)H₂ from the FSi₂H₅ decomposition in the presence of C₂H₅SiH₃ was about 21, it is obvious that SiH₂ insertion into C₂H₅SiH₃ was considerably greater than that of FSiH.

The relative half-life of SiF_2 is about 10^5 greater than that

of SiCl₂.^{23,24} From this, we assume that the half-life of HSiF is greater than that of HSiCl. Our data would then suggest that HSiCl inserts into silicon-hydrogen bonds faster than HSiF.

Our data with half-life assumptions (FSiH > ClSiH > SiH₂) suggest relative rates of silylene insertions into the silicon-hydrogen bonds of $C_2H_5SiH_3$ are in the order SiH₂ > ClSiH > FSiH \ge SiCl₂, SiF₂. 3. Decomposition Modes of Disilanes. Methyldisilane⁴

3. Decomposition Modes of Disilanes. Methyldisilane⁴ and $1,1-(CH_3)_2Si_2H_4^{25}$ decompose by both available 1,2 hydrogen shift routes in nearly statistical ratios. It is obvious that this observation cannot be made for the halodisilanes, especially for 1,1-F₂Si₂H₄ where only one route was observed.

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Registry No. Si₂F₆, 13830-68-7; 1,1-F₂Si₂H₄, 15857-41-7; F-Si₂H₅, 14537-73-6; 1,1-Cl₂Si₂H₄, 20424-84-4; ClSi₂H₅, 14565-98-1; *sym*-Cl₂Si₂H₂(CH₃)₂, 42087-66-1; F₂Si₃H₆, 42086-09-9; 1-FSi₃H₇, 34551-82-1; 1-ClSi₃H₇, 31411-99-1; Cl₂Si₃H₃(CH₃)₃, 42086-10-2; C₂H₅Si₂H₂D₃, 42087-69-4; C₂H₅Si₂H₄F, 42087-70-7; C₂H₅Si₂HD₃F, 42087-71-8; C₂H₅Si₂HD₃Cl, 42087-72-9; C₂H₅Si₂H₄Cl, 42087-73-0.

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Nature and Stability of the CuCl⁺ Complex in Aqueous Solution

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Equimolal mixtures of the divalent transition metal perchlorates with magnesium perchlorate are proposed as effectively constant ionic media for the study of weak complexes of the type MX (M = a divalent metal cation, X = anion). Values of the stability constant, β_1 , and the molar absorption coefficient, ϵ , of the CuCl⁺ complex have been determined in equimolal mixtures of copper(II) perchlorate with magnesium(II) perchlorate of the total molalities of 0.40, 1.34, and 2.39 mol kg⁻¹. ϵ is found to be approximately constant (1115 \mp 80) in dilute and moderately concentrate solutions, while at the highest concentrations of the ionic medium a slight increase in its value takes place, as indicated by additional experiments involving solutions of varying concentration of copper(II) perchlorate and a small concentration of NaCl. From the independent-ly determined product $\epsilon\beta_1^{\circ}$, the value of $1.63 \mp 0.15 \text{ mol}^{-1} \text{ dm}^3$ is found for β_1° , the thermodynamic equilibrium constant of the Cu²⁺ + Cl⁻ \Rightarrow CuCl⁺ reaction at 25°. The variation in the quotient of the activity coefficients of the latter reaction with the concentration of either copper(II) perchlorate or magnesium(II) perchlorate has also been calculated from the spectrophotometric data and is found to be practically the same for the two ionic media. The nature of the CuCl⁺ complex is discussed on the basis of its uv and visible spectral characteristics and the conclusion is drawn that it consists mainly of the [CuCl(OH₂)₆]⁺ coordination complex, in which the chloride anion replaces one of the two more distant water molecules of the hexaquo complex, with a small contribution of the [Cu(OH₂)₆]²⁺Cl⁻+ outer-sphere ion pair.

Introduction

Constant ionic media are commonly used in determinations of the stability constants of metal complexes in order to maintain constant activity coefficients of reacting species.¹ However, this method becomes unsatisfactory when the ligands are ionic and the stabilities of complexes under investigation are low. It is necessary, in such cases, to vary the concentration of the complexing anion over a broad range, considerably changing, at the same time, the activity coefficients of the reacting species. Adjusting the concentration of the ionic medium so as to obtain a constant formal ionic strength does not, of course, fix the activity coefficients. The difficulties were discussed by Matheson in connection with the determination of the stability constant of the CuSO₄ complex in aqueous solution.² A new possibility of controlling the activity coefficients in determinations of stability constants of weak anionic complexes arises from our recent observations concerning the activity coefficients in aqueous solutions of a group of divalent metal perchlorates. It has been shown that equimolal solutions, pure or mixed, of Mn(ClO₄)₂,

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